



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Avi Tepman et al.

§ Group Art Unit: 2823

Serial No.: 10/074,854

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Filed: February 11, 2002

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Title: Variable Flow Deposition Apparatus  
And Method in Semiconductor  
Substrate Processing.

§ Examiner: W. David Coleman

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§ Attorney Docket No.:AM5018/ISM

Date: July 15, 2003

**RESPONSE TO RESTRICTION REQUIREMENT UNDER 37 C.F.R. 1.143**

**Hon. Commissioner of Patents and Trademarks  
Washington, D.C. 20231**

Sir:

The present communication is in response to the Office Action dated June 27, 2003, outlining the Examiner's restriction requirement between Method Claims 1-27 and Apparatus Claims 28-51.

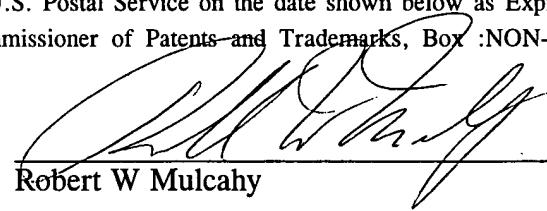
In response to the Examiner's requirement of ~~selection~~ of claims, Applicant's undersigned Attorney hereby elects Method Claims 1-27 for prosecution, with traverse.

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**EXPRESS MAIL UNDER 37 CFR 1.10**

I hereby declare that this paper is being deposited with the U.S. Postal Service on the date shown below as Express Mail, Mailer No. EL341110851US addressed to the: Commissioner of Patents and Trademarks, Box :NON-Fee Amendment, P.O. BOX 1450, Alexandria, VA 22312-1450.

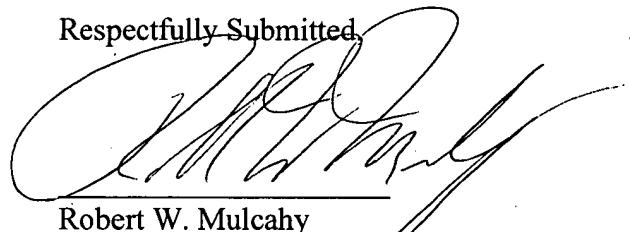
Date 07/15/03

  
Robert W Mulcahy

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Applicant's undersigned attorney invites any direct telephone communication from the Examiner to expedite prosecution of the subject Application.

Respectfully Submitted,



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